



H-811

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

N. KOFUJI et al

Serial No. 09/363,191

Group Art Unit: 1765

Filed: July 29, 1999

Examiner: L. Alejandro Mulero

For: DRY ETCHING APPARATUS AND A METHOD OF
MANUFACTURING A SEMICONDUCTOR DEVICE

RESPONSE TO RESTRICTION REQUIREMENT


Commissioner of Patents
Washington, D.C. 20231

Sir:

In response to the Restriction Requirement mailed
February 13, 2001, applicants elect Group A, Claims 1-9,
directed to the first embodiment of the invention, without
traverse.

The Commission is hereby authorized to charge any fees
due in connection with this response to Deposit Account No.
50-1417.

Respectfully submitted,


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